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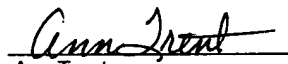
Applicant: Daniel R. Caldwell, et al. Docket No: TI-36721
Serial No: 10/706,762 Conf. No: 7834
Examiner: Dung V. Nguyen Art Unit: 3723
Filed: 11/10/2003
For: CHEMICAL MECHANICAL POLISHING SLURRY PUMP MONITORING SYSTEM AND METHOD

AMENDMENT PURSUANT TO 37 CFR 1.116

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P.O. Box 1450
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MAILING CERTIFICATE UNDER 37 C.F.R. § 1.8(a)

I hereby certify that the above correspondence is being deposited with the U.S. Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 5-26-05.


Ann Trent

Dear Sir:

Responsive to the Office Action mailed March 25, 2005, in connection with the above identified application, Applicants respectfully submit the following amendments and remarks.